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**INFORMATION DISCLOSURE  
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Sheet 1 of 4

**Complete If Known**

Application Number	10/665,900
Filing Date	September 19, 2003
First Named Inventor	Fréchet, Jean M.J., et. al.
Art Unit	1743
Examiner Name	Not yet assigned
Attorney Docket Number	JB-1829

**U.S. PATENT DOCUMENTS**

Examiner	Cite No.	Document Number		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code <sup>2</sup> (if known)			
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**OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS**

Examiner Initials <sup>1</sup>	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
/JN/	AQ	ALLMER K, Hult A, Ranby B., Surface modification of polymers. II: Grafting with glycidyl acrylate and the reactions of the grafted surface with amines. <i>J. Polym Sci Polym Chem</i> 1989; 27:1641-52.	
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/JN/	AU	BARKER S. L. R., Tarkov MJ, Canavan H, Hickman JJ, and Locascio LE, "Plastic Microfluidic Devices Modified with Polyelectrolyte Multilayers", <i>Anal. Chem.</i> ; 2000; 72(20) pp 4899 - 4903.	

Examiner Signature	/Jyoti Nagpaul/	Date Considered	03/28/2007
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